

# WS-1000MH Mini Station



## Engineered

An advanced coating, etching, developing, or cleaning system, mounted in a work station, designed and built for you and your process.

## Capable

Can be configured with systems for processing wafers up to 300 mm.

Optional Touch Interface for the most powerful and flexible control system available.

## Safe

Chemical containment, leak detection, sensors, interlocks, and alarms provide essential protection for the operator.



**Telephone:** 215-699-7278  
**Fax:** 215-699-4311  
**Email:** sales@laurell.com

Laurell Technologies Corporation  
1400 Pennbrook Parkway  
Lansdale, PA 19446

# WS-1000 Full Station



**Laurell Technologies** has 28 years of experience with our customers' complex processes, multiple chemistries, safety issues, waste containment, and disposal issues.

**Benefit from our expertise and let us engineer your convenient solution.**

## **WS-1000 Full Station**

*EDC-650-8NPP & EDC-650-8TFM*

*With Optional Touch Screen Interface*

## **Options and Accessories**

**Touch Screen Interface:** Control, program and monitor all operations with a touch.

**Bluetooth® Wireless Technology**

**Rinse to Resistivity:** Detects rinse completion and alerts the processor to dry the substrate, saving valuable resources usually wasted on a time-based system.

**Multi-Position Non-Contact Level Sensing:** Either in a drain reservoir or supply container - fully programmable.

**Leak Detection:** Laurell uses the most dependable sensor technology available - audible and visual alarms with industry-standard light tree.

**Heated Process Chemistry:** with point-of-use or recirculation type heat exchangers.

**Teflon® Spin Housing:** We only use **semiconductor grade Teflon®** with **zero porosity** to prevent "chemical memory" effects (processor shown on right above).

*Teflon® is a registered trademark of E. I. du Pont de Nemours & Co.*

